ABSTRACT

IMPROVED SEMICONDUCTOR MANUFACTURING SYSTEM

An improved manufacturing system for processing semiconductor wafers which includes a (1) plurality of processing stations, (2) a sealed transport tunnel located directly over the processing stations, (3) a transport means to move wafers within the tunnel, (4) interconnection chambers joining the transport tunnel and the processing stations, (5) interface mechanisms in the interconnection chambers to move the wafers to and from the processing stations, and (6) a computer means to control the operations of the transport means, the interface mechanisms, and the processing equipment at the processing stations.

(FIGURE 1 IS SUGGESTED FOR PUBLICATION)